

# A new reaction mode of germanium-silicon bond formation: insertion reactions of $\text{H}_2\text{GeLiF}$ with $\text{SiH}_3\text{X}$ ( $\text{X}=\text{F}, \text{Cl}, \text{Br}$ )

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**Abstract** A combined density functional and *ab initio* quantum chemical study of the insertion reactions of the germolenoid  $\text{H}_2\text{GeLiF}$  with  $\text{SiH}_3\text{X}$  ( $\text{X}=\text{F}, \text{Cl}, \text{Br}$ ) was carried out. The geometries of all the stationary points of the reactions were optimized using the DFT B3LYP method and then the QCISD method was used to calculate the single-point energies. The theoretical calculations indicated that along the potential energy surface, there were one precursor complex (Q), one transition state (TS), and one intermediate (IM) which connected the reactants and the products. The calculated barrier heights relative to the respective precursors are 102.26 ( $\text{X}=\text{F}$ ), 95.28 ( $\text{X}=\text{Cl}$ ), and 84.42 ( $\text{X}=\text{Br}$ )  $\text{kJ mol}^{-1}$  for the three different insertion reactions, respectively, indicating the insertion reactions should occur easily according to the following order:  $\text{SiH}_3\text{-Br} > \text{SiH}_3\text{-Cl} > \text{SiH}_3\text{-F}$  under the same situation. The solvent effects on the insertion reactions were also calculated and it was found that the larger the dielectric constant, the easier the insertion reactions. The elucidations of the mechanism of these insertion reactions provided a new reaction model of germanium-silicon bond formation.

**Keywords** B3LYP ·  $\text{H}_2\text{GeLiF}$  · Insertion reaction · QCISD ·  $\text{SiH}_3\text{X}$  ( $\text{X}=\text{F}, \text{Cl}, \text{Br}$ )

## Introduction

The research of germanium compounds and their reactions is an interesting topic since many organic germanium compounds have been found to have biologic activities [1–4]. The theoretical study and complementary experiments of

germanium compounds have made dramatic advances over the past few years [5–15].

Germolenoid  $\text{R}_1\text{R}_2\text{GeMX}$  ( $\text{M}=\text{alkali metal}, \text{X}=\text{halogen}$ ) is one of the derivatives of germylene. As analogous to carbenoid  $\text{R}_1\text{R}_2\text{CMX}$  [16, 17] and silylenoid  $\text{R}_1\text{R}_2\text{SiMX}$  [18, 19], germolenoid may be more stable than germylene  $\text{R}_1\text{R}_2\text{Ge}$  and has some particular reactive properties. In 1991, Gaspar et al. [20] firstly suggested that germolenoid might be the intermediate involved in the reaction of dichlorodimethylgermane with substituted butadiene in THF solvent. In 2000, Ichinohe et al. [21] pointed out that in the reaction of  $\text{GeCl}_2 \cdot \text{dioxane}$  with  ${}^t\text{Bu}_3\text{SiNa}$ , one germolenoid  ${}^t\text{Bu}_3\text{SiGeCl}_2\text{Na}$  was a reactive intermediate. In 2005, Tajima et al. [10] synthesized extremely hindered bis(germacyclopropa)benzenes. The authors [10] considered that the formation of bis(germacyclopropa)benzenes should be interpreted in terms of the concurrent generation of different reactive species such as the intermediate germolenoid  $\text{Tbt}(\text{Dip})\text{GeBrLi}$  and benzyne species in the reaction under the mild conditions. In 2006, Sasamori et al. [22] described the initial work on the sila- and germacyclopropabenzenes. They thought that germolenoid  $\text{Tbt}(\text{Dip})\text{GeLiBr}$  was an important intermediate in the addition reaction. Very recently, Filippou et al. [23] synthesized some compounds containing metal-germanium triple bonds and in this work the germolenoid should be an important reactant. However, no stable germolenoid has been synthesized successfully till now. Therefore, it is necessary to carry out systemic theoretical study on germolenoids to investigate their structures, properties, and reactions.

There were some theoretical works on germolenoid. In 1999, Qiu et al. [24] firstly examined the isomeric structure of the simplest germolenoid  $\text{H}_2\text{GeLiF}$  by *ab initio* calculations. Until now, a few kinds of germolenoids have been investigated such as  $\text{H}_2\text{GeLiX}$  [24–27],  $\text{H}_2\text{GeNaF}$  [28],  $\text{H}_2\text{GeClMgCl}$  [29],  $\text{H}_2\text{GeClAlCl}_2$  [30],  $\text{H}_2\text{GeClBeCl}$  [31],  $\text{HB}=\text{GeLiF}$  [32],  $\text{H}_2\text{C}=\text{GeNaF}$  [33], and  $\text{HN}=\text{GeNaF}$  [34]. As aforementioned, germolenoid was active intermediate and

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played important roles in many organic reactions [20–23]. If people understand the reactivity of germylenoid correctly, the proper methods would be carried out to synthesize new germanium-containing compounds using germylenoid. Therefore it is necessary to study the reactions of the germylenoid with other substances systemically. To our best knowledge, theoretical studies on the reactions of germylenoids were not many and only some reactions of germylenoids with small molecules, such as HF, H<sub>2</sub>O, NH<sub>3</sub>, CH<sub>4</sub>, and CH<sub>3</sub>X (X=F, Cl, Br) [27, 28, 32, 34–37] have been calculated. However, the insertion reactions of germylenoid into Si–X bonds have not been reported. In order to fill this gap and extend the reactions of the germylenoid, we have investigated the insertion reactions of the germylenoid H<sub>2</sub>GeLiF with SiH<sub>3</sub>X (X=F, Cl, Br) using the density functional and *ab initio* quantum chemical calculations recently. Through this theoretical work, we hope (i) to optimize the structures of all stationary points, (ii) to determine the thermodynamics of the insertion reactions, (iii) to predict their activation barriers, (iv) to elucidate the reaction mechanisms, and (v) to evaluate the solvent effects on the insertion reactions of H<sub>2</sub>GeLiF with SiH<sub>3</sub>X (X=F, Cl, Br). The elucidations of the mechanism of these insertion reactions would provide a new reaction model of germanium–silicon bond formation.

## Computational methods

The computational details were described elsewhere [36]. The geometries for the stationary points were computed with the Gaussian 09 program suits [38]. The DFT (density functional theory) B3LYP (Becke's three-parameter hybrid function with the non-local correlation of Lee–Yang–Parr) [39, 40] method with the 6-311+G (d, p) [41] basis set were used for all computations. All geometries were first optimized and then the harmonic vibrational frequencies were calculated at the same level to confirm the properties of the stationary points. The insertion reaction pathways for the mechanism discussed were verified using intrinsic reaction coordinate (IRC) [42] analyses for all TS structures to verify the reactants and the products to which each TS was connected. The electrostatic potential computations were carried out on the optimum geometries at the B3LYP/6-311+G (d, p). In order to improve the treatment of electron correlation, the single-point calculations were performed at the QCISD [43, 44] level using the 6-311++G(d, p) basis set for all atoms. Unless otherwise noted, the relative energies given in the present paper were those determined at QCISD/6-311++G(d, p)//B3LYP/6-311+G (d, p) and included zero-point vibrational energy (ZPE, without scale) corrections determined at B3LYP/6-311+G (d, p) level. To consider solvent effects on the insertion reactions, the PCM (polarized continuum model) [45–47] was applied to the calculations. The solvents cyclohexane (C<sub>6</sub>H<sub>12</sub>, dielectric constant

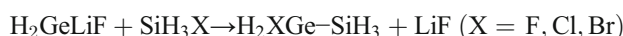
$\epsilon=2.016$ ), tetrahydrofuran (THF,  $\epsilon=7.426$ ), acetone (CH<sub>3</sub>COCH<sub>3</sub>,  $\epsilon=20.493$ ), methyl alcohol (CH<sub>3</sub>OH,  $\epsilon=32.613$ ), dimethyl sulfoxide (DMSO,  $\epsilon=46.826$ ), and water (H<sub>2</sub>O,  $\epsilon=78.355$ ) were used.

## Results and discussion

The previous calculations [24, 27] show that germylenoid H<sub>2</sub>GeLiF had three equilibrium configurations, in which the *p*-complex structure had the lowest energy and was the most stable structure. Consequently, the *p*-complex structure of H<sub>2</sub>GeLiF was selected as the reactant when we analyzed the insertion reactions of germylenoid H<sub>2</sub>GeLiF with SiH<sub>3</sub>X (X=F, Cl, Br).

As shown in Fig. 1, the *p*-complex germylenoid H<sub>2</sub>GeLiF can be regarded as a singlet complex in which electrons of the F atom in LiF are donated into the empty *p*-orbital of Ge atom in H<sub>2</sub>Ge. The electrostatic potential computations indicate that in SiH<sub>3</sub>X there is more negative charge lying on the halogen atom X and positive charge lying on the silicon atom. When SiH<sub>3</sub>X approaches germylenoid H<sub>2</sub>GeLiF with the halogen atom X and SiH<sub>3</sub> attacking the unoccupied *p*-orbital and the  $\sigma$  lone-pair electrons of Ge atom respectively, insertion reactions take place.

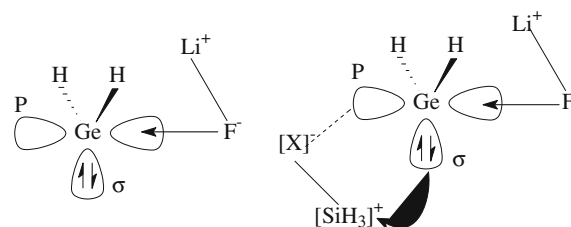
The insertion reactions of germylenoid H<sub>2</sub>GeLiF with SiH<sub>3</sub>X (X=F, Cl, Br) could be described as the following formula:



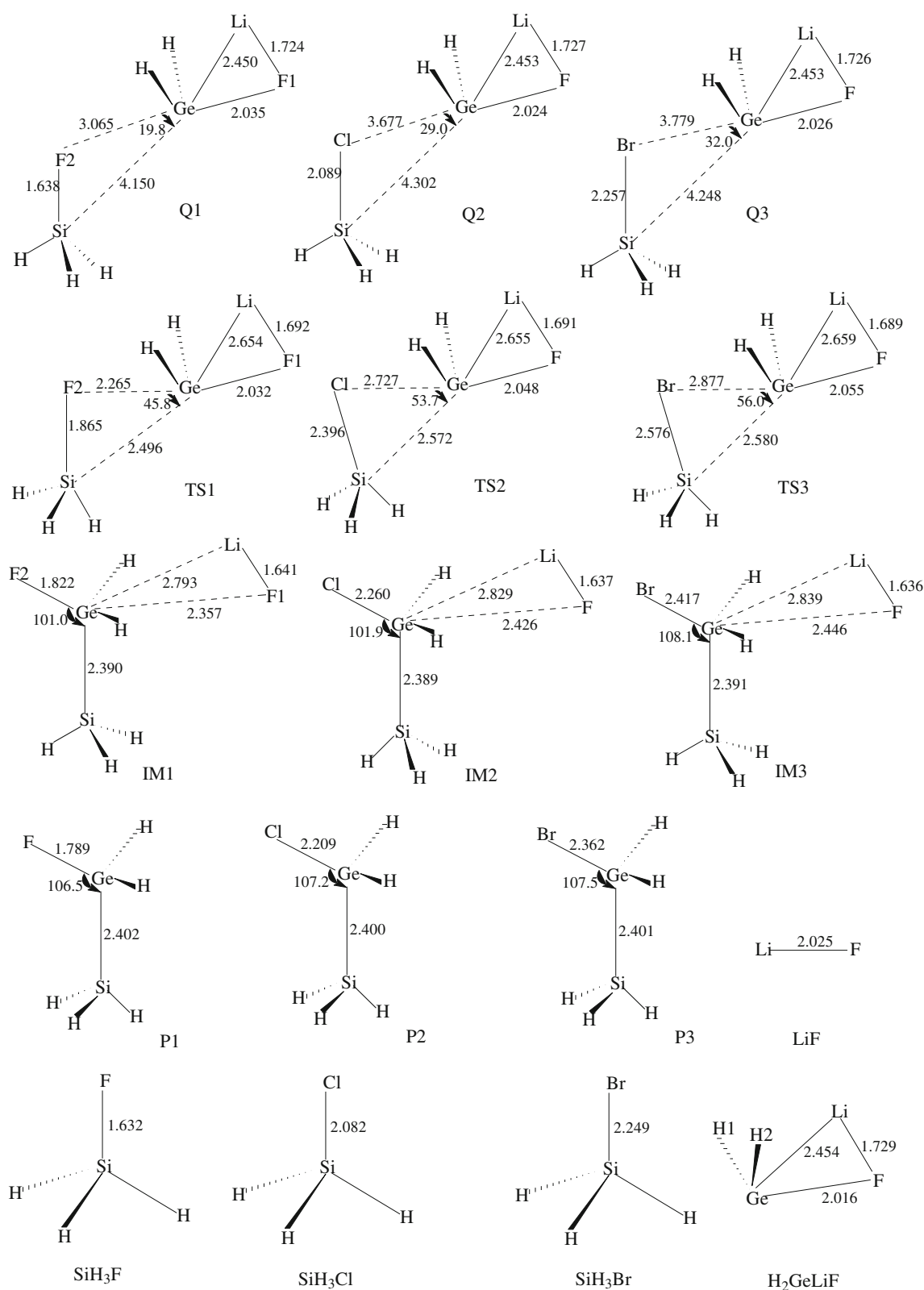
Based on the calculated results, we found that there are one precursor complex (Q), one transition state (TS), and one intermediate (IM) which connected the reactants and the products along the potential energy surface. The geometries of reactants, Qs, TSs, IMs, and products are shown in Fig. 2.

### The structures and energies of the precursor complexes

When halogenated silane SiH<sub>3</sub>X approaches germylenoid H<sub>2</sub>GeLiF, the initial formation of the precursor complexes Q1, Q2, and Q3 are facilitated by the interaction between the



**Fig. 1** The *p*-complex H<sub>2</sub>GeLiF and its insertion reaction paths with SiH<sub>3</sub>X (X=F, Cl, Br)



**Fig. 2** The geometries of the stationary points of the insertion reactions of the gemylenoid  $\text{H}_2\text{GeLiF}$  with  $\text{SiH}_3\text{X}$  ( $\text{X}=\text{F}, \text{Cl}, \text{Br}$ ) in gas phase calculated at B3LYP/6-311+G (*d, p*) level (Bond lengths are given in angstroms and angles in degrees)

*p*-orbital on Ge atom and the negative X atom of  $\text{SiH}_3\text{X}$ . The precursor complexes adopt  $C_1$  symmetry and involve

inversion of configuration. Compared with the separated structures of  $\text{SiH}_3\text{X}$  and  $\text{H}_2\text{GeLiF}$  molecules, the moieties of

$\text{SiH}_3\text{X}$  and  $\text{H}_2\text{GeLiF}$  in Q1, Q2, and Q3 change very little, respectively. From Fig. 2, it can be seen that the Ge-X (X=F, Cl, Br) bond lengths in Q1, Q2, and Q3 are very long, and the Si-X bonds are found to be slightly longer than their corresponding Si-X bond lengths in the isolated reactants  $\text{SiH}_3\text{X}$ . The energies of the precursor complexes Q1, Q2, and Q3 are lower than their corresponding reactants by 7.23, 8.49, and 8.47  $\text{kJ mol}^{-1}$ , respectively (Table 1). The long Ge-X bond lengths, the slight elongation of Si-X bond lengths, and the small relative energies of the precursor complexes (Q1, Q2, and Q3) indicate that the interaction of Ge atom and X atom is very weak.

#### The structures and energies of the transition states

Based on the electrostatic potential computations, we found that there is a positive  $\sigma$  hole on Si. When  $\text{SiH}_3$  gradually approaches the  $\sigma$  lone-pair electrons of Ge atom, the TSs create. As displayed in Fig. 2, the calculated transition states TS1, TS2, and TS3 in the insertion reactions have the similar structures. There is a three-membered-ring structure (Si-Ge-X, X=F, Cl, Br) in each TS. The Si-X bond broken in TSs are lengthened by 0.233 (X=F), 0.314 (X=Cl), 0.327 Å (X=Br), compared to the isolated  $\text{SiH}_3\text{X}$ , where the bond elongation correspond to about 14.3, 15.1, and 14.5 % of its original length, respectively. These reveal that the migrating halogen atom X has a strong reactant-like character. On the other hand, the Ge-X bonds forming in TSs are found to be greatly shorter than their corresponding Ge-X bond lengths in the Qs. The bond angles X-Ge-Si increase from Qs toward TSs, by 26.0, 24.7, and 24.0°, respectively. According to the Hammond's postulate [48], the three transition states are all early TSs.

The frequency analysis calculations are made at the B3LYP/6-311+G (d, p) level. The calculations indicate that all TSs have unique imaginary frequency, which are 130.0i, 245.6i, and 209.4i  $\text{cm}^{-1}$ , respectively. The unique imaginary frequency vibration involves bond formation between Ge and Si in concert with Si-X bond breaking, and X migration to Ge. The IRC calculations displayed that the transition states

connected the precursor complexes and the intermediates. As listed in Table 1, the relative energies of TS1, TS2, and TS3 to their reactants are 95.03, 86.79, and 75.95  $\text{kJ mol}^{-1}$ , respectively. Therefore, the reaction barriers relative to the respective precursors are 102.26 (X=F), 95.28 (X=Cl), and 84.42  $\text{kJ mol}^{-1}$  (X=Br), respectively.

#### The structures and energies of the intermediates and products

As shown in Fig. 2, three intermediates of the three insertion reactions have similar bipyramid structures formed between Ge atom and its adjacent atoms. The bond angles X-Ge-Si (X=F, Cl, Br) increase dramatically from TSs toward IMs, by 55.2, 48.2, and 46.3°, respectively. In the IMs, the Si-X bonds have been broken completely. The Ge-Si and Ge-X (X=F, Cl, Br) bond lengths of IMs are shorter than those of TSs respectively. The Ge-Si bond lengths of IMs are 0.106, 0.183, 0.189 Å shorter than those of TSs and Ge-X (X=F, Cl, Br) bond lengths obviously decrease from TSs toward IMs, by 0.443, 0.467, and 0.460 Å. The shortening of the Ge-Si and Ge-X (X=F, Cl, Br) bond lengths indicate that the Ge-Si and Ge-X (X=F, Cl, Br) bond have been almost formed. As listed in Table 1, the relative energies of IM1, IM2, and IM3 to their reactants are -2.16, -56.55, and -64.68  $\text{kJ mol}^{-1}$ , respectively.

After getting over the transition states, the IMs can further decompose to substituted germane  $\text{H}_2\text{XGe-SiH}_3$  and LiF, which are the products of the insertion reactions of  $\text{H}_2\text{GeLiF}$  and  $\text{SiH}_3\text{X}$  (X=F, Cl, Br). The LiF moiety leaving from Ge atom is monotonously energy increasing process. The sum of the energies of  $\text{H}_2\text{XGe-SiH}_3$  and LiF are above the energies of IMs by 62.54, 52.92, 50.40  $\text{kJ mol}^{-1}$ , respectively. Compared with the reactants, the relative energies of the final products ( $\text{H}_2\text{XGe-SiH}_3 + \text{LiF}$ ) are 60.38 (X=F), -3.63 (X=Cl), and -14.28  $\text{kJ mol}^{-1}$  (X=Br), respectively.

#### The mechanisms of the insertion reactions

Here we choose the insertion reaction of  $\text{H}_2\text{GeLiF}$  with  $\text{SiH}_3\text{Cl}$  as an example. IRC calculations have been performed

**Table 1** Relative energies<sup>a</sup> (in  $\text{kJ mol}^{-1}$ ) of precursor complexes (Qs), transition states (TSs), intermediates (IMs), and products in solvents

Solvents	Q1	TS1	IM1	P1+LiF	Q2	TS2	IM2	P2+LiF	Q3	TS3	IM3	P3+LiF
Gas phase	-7.23	95.03	-2.16	60.36	-8.49	86.79	-56.55	-3.63	-8.47	75.95	-64.68	-14.28
$\text{C}_6\text{H}_{12}$	-7.45	73.31	-19.98	28.50	-8.97	66.97	-74.51	-35.86	-8.78	57.28	-82.49	-45.75
THF	-6.20	56.75	-30.78	3.11	-8.20	52.49	-85.02	-60.62	-7.90	43.42	-92.72	-70.29
Acetone	-5.79	52.34	-33.73	-2.96	-7.90	48.60	-87.95	-66.53	-7.57	39.64	-95.57	-76.14
Methanol	-5.69	51.39	-34.36	-4.22	-7.82	47.76	-88.59	-67.75	-7.50	38.82	-96.20	-77.35
DMSO	-5.63	50.90	-34.70	-4.86	-7.78	47.33	-88.92	-68.38	-7.45	38.39	-96.52	-77.97
$\text{H}_2\text{O}$	-5.58	50.45	-35.00	-5.44	-7.74	46.93	-89.23	-68.95	-7.41	38.00	-96.83	-78.54

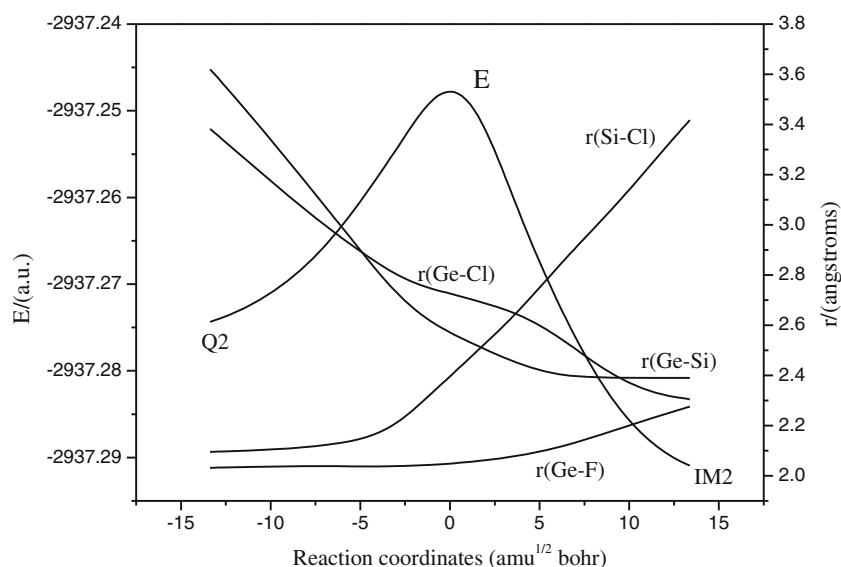
<sup>a</sup> Calculated at the QCISD/6-311++G(d, p)/B3LYP/6-311+G(d, p) level

on the basis of the optimized TS2 to investigate the interaction between  $\text{H}_2\text{GeLiF}$  and  $\text{SiH}_3\text{X}$  in the insertion process. The total energy changes and the variations of Ge-F, Ge-Cl, Ge-Si, and Si-Cl bond distances along the IRC path are shown in Fig. 3. From Fig. 3, it can be seen that as the reaction coordinate passes from point  $-5.0$  to  $0.0$ , the total energy increases sharply and reaches its maximum at point  $0.0$ . In this region, the lengths of Ge-F and Si-Cl bond increase and the lengths of Ge-Si and Ge-Cl bond decrease obviously. As for the Si-Cl and Ge-Cl bond distances, they increase and decrease with the proceeding of the reaction, implying the break of the former and the formation of the latter, respectively. We think the insertion reactions of  $\text{H}_2\text{GeLiF}$  with  $\text{SiH}_3\text{X}$  ( $\text{X}=\text{F}, \text{Br}$ ) have a similar mechanism with  $\text{H}_2\text{GeLiF}+\text{SiH}_3\text{Cl}$  reaction.

#### The comparisons of three insertion reactions

The calculated barrier heights relative to the respective precursors are  $102.26$  ( $\text{X}=\text{F}$ ),  $95.28$  ( $\text{X}=\text{Cl}$ ), and  $84.42$  ( $\text{X}=\text{Br}$ )  $\text{kJ mol}^{-1}$  for the three different insertion reactions, respectively, revealing their different reactivities. Consequently, the calculated relative reaction free energies of them are  $60.38$  ( $\text{X}=\text{F}$ ),  $-3.63$  ( $\text{X}=\text{Cl}$ ),  $-14.28$   $\text{kJ mol}^{-1}$  ( $\text{X}=\text{Br}$ ), respectively. Consequently, from the thermodynamic and kinetic viewpoints, the insertion reactions  $\text{H}_2\text{GeLiF}$  plus  $\text{SiH}_3\text{X}$  should occur easily according to the following order:  $\text{SiH}_3\text{-Br} > \text{SiH}_3\text{-Cl} > \text{SiH}_3\text{-F}$  under the same situation. This order can be explained by comparing the Si-X bond energies. For Si-F, Si-Cl, and Si-Br, the bond energies are  $565$ ,  $381$ , and  $310$  [49]  $\text{kJ mol}^{-1}$ , respectively. Therefore, among the three reactions, the  $\text{H}_2\text{GeLiF}+\text{SiH}_3\text{F}$  is the most difficult to react, the reaction of  $\text{H}_2\text{GeLiF}$  with  $\text{SiH}_3\text{Cl}$  is much easier than with  $\text{SiH}_3\text{F}$ , and the reaction of  $\text{H}_2\text{GeLiF}+\text{SiH}_3\text{Br}$  is the easiest.

**Fig. 3** The changes of energies and bond distances along the reaction coordinates of the reaction of  $\text{H}_2\text{GeLiF}+\text{SiH}_3\text{Cl}$



#### The solvent effect

To consider the solvent effects on these reactions, using the PCM model and the  $\text{C}_6\text{H}_{12}$ , THF, acetone, methyl alcohol, DMSO, and  $\text{H}_2\text{O}$  solvents, the QCISD/6-311++G(d, p) single-point calculations were performed at the B3LYP/6-311+G(d, p) optimized geometries. The relative energies of all stationary points calculated in various solvents are also listed in Table 1. It can be seen from Table 1 that the relative energies of the TSs, IMs, and products for the three insertion reactions calculated in various solvents are lower respectively than those calculated in gas phase. Compared with those in gas phase, the barrier heights in various solvents are lower, implying insertion reactions of  $\text{H}_2\text{GeLiF}$  with  $\text{SiH}_3\text{X}$  are easier to occur in solvents. On the other hand, it can be seen from Table 1, with the raising of dielectric constant, the insertion reactions occur more easily. Therefore, the insertion reactions of  $\text{H}_2\text{GeLiF}$  with  $\text{SiH}_3\text{X}$  occur easily according to the following order:  $\text{H}_2\text{O} > \text{DMSO} > \text{methyl alcohol} > \text{acetone} > \text{THF} > \text{C}_6\text{H}_{12} > \text{gas phase}$ .

#### Comparisons of the insertion reactions of $\text{H}_2\text{GeLiF}$ with $\text{SiH}_3\text{X}$ and $\text{CH}_3\text{X}$ ( $\text{X}=\text{F}, \text{Cl}, \text{Br}$ )

We [37] have studied the insertion reactions of  $\text{H}_2\text{GeLiF}$  with  $\text{CH}_3\text{X}$  ( $\text{X}=\text{F}, \text{Cl}, \text{Br}$ ) using the DFT B3LYP and QCISD methods. By comparing with the present work and reference [37], we can find some facts as follows: (a) the mechanisms of the two kinds of insertion reactions are identical; (b) The reaction barriers of the insertion reactions of  $\text{H}_2\text{GeLiF}$  with  $\text{SiH}_3\text{X}$  are lower than those with  $\text{CH}_3\text{X}$ , respectively, indicating that the insertion reactions of  $\text{H}_2\text{GeLiF}$  with  $\text{YH}_3\text{X}$  ( $\text{Y}=\text{C}, \text{Si}$ ) occur easily according to the following order:  $\text{SiH}_3\text{X} > \text{CH}_3\text{X}$  under the same situation. For example, when  $\text{X}=\text{Cl}$ , the

reaction barrier of the insertion reaction of  $\text{H}_2\text{GeLiF}$  with  $\text{SiH}_3\text{Cl}$  is  $95.28 \text{ kJ mol}^{-1}$ , while the reaction barrier of the insertion reaction of  $\text{H}_2\text{GeLiF}$  with  $\text{CH}_3\text{Cl}$  is  $238.01 \text{ kJ mol}^{-1}$  [37]. Obviously, under the same situation, the reaction of  $\text{H}_2\text{GeLiF} + \text{SiH}_3\text{Cl}$  occurs easier than  $\text{H}_2\text{GeLiF} + \text{CH}_3\text{Cl}$ ; (c) For both kinds of reactions, the solvent effects are similar: in solvents, the insertion reactions occur easier than in vacuum.

## Conclusions

In this work, we studied the insertion reactions of the germylenoid  $\text{H}_2\text{GeLiF}$  with  $\text{SiH}_3\text{X}$  ( $\text{X} = \text{F}, \text{Cl}, \text{Br}$ ) for the first time by using the DFT B3LYP and QCISD methods. The theoretical calculations indicated that along the potential energy surface, there were one precursor complex (Q), one transition state (TS), and one intermediate (IM) which connected the reactants and the products. The reactions proceeded through a three-member-ring transition state structure, involving the Ge atom, the Si atom, and the migrating halogen X atom. The three reactions generally followed a similar reactivity pattern. From the thermodynamic and kinetic viewpoints, the calculated results indicated that under the same condition the insertion reactions should occur easily according to the following order:  $\text{SiH}_3\text{-Br} > \text{SiH}_3\text{-Cl} > \text{SiH}_3\text{-F}$ . The solvent effects on the insertion reactions were also calculated and it was found that the larger the dielectric constant, the easier the insertion reactions.

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